

Contents

SESSION 1

- 3 **Overview of variable-angle spectroscopic ellipsometry (VASE): I. Basic theory and typical applications**
J. A. Woollam, B. D. Johs, C. M. Herzinger, J. N. Hilfiker, R. A. Synowicki,
C. L. Bungay, J.A. Woollam Co., Inc.
- 29 **Overview of variable-angle spectroscopic ellipsometry (VASE): II. Advanced applications**
B. D. Johs, J. A. Woollam, C. M. Herzinger, J. N. Hilfiker, R. A. Synowicki,
C. L. Bungay, J.A. Woollam Co., Inc.

SESSION 2

- 61 **Analysis of low dielectric constant and Cu-based single- and multilayered films using spectroscopic ellipsometry**
A. R. Srivatsa, C. L. Ygartua, KLA-Tencor Corp.
- 78 **In-situ ellipsometry: applications to thin film research, development, and production**
M. T. Kief, Seagate Technology

SESSION 3

- 109 **Optical scatter measurements and their application to surface metrology**
J. C. Stover, ADE Optical Systems
- 129 **Optical scatterometry for process metrology**
S. S. H. Naqvi, GIK Institute of Engineering Sciences and Technology
(Pakistan); J. R. McNeil, Univ. of New Mexico

SESSION 4

- 147 **Milestones and future directions in applications of optical scatterometry**
C. J. Raymond, Bio-Rad Labs., Inc.

SESSION 5

- 181 **Time-resolved scanning Kerr microscopy in magnetic dynamics investigations**
A. Stankiewicz, W. K. Hiebert, G. E. Ballentine, M. R. Freeman, Univ.
of Alberta (Canada)
Optical Metrology: A Critical Review, edited by Ghanim A. Al-Jumaily, Proc. of SPIE Vol. 10294 (Vol. CR72),
1029401 · © (1999) 2017 SPIE · CCC code: 0277-786X/17/\$18 · doi: 10.1117/12.2284243

SESSION 6

- 213 **Multitype surface and thin film characterization using light scattering, scanning force microscopy, and white light interferometry**
A. Duparré, G. Notni, Fraunhofer Institute for Applied Optics and Precision Engineering (Germany)
- 232 **High-resolution imaging of heterogeneous surfaces with multifunctional NSOM**
J. Kerimo, M. Büchler, W. H. Smyrl, Univ. of Minnesota/Twin Cities
- 257 **Nonlinear optical characterization of organic materials**
M. M. Bader, The Pennsylvania State Univ.